

IN THE CLAIMS

Please amend the claims as follows:

1. (currently amended) A method for producing a preform for optical fibers ~~[by]~~ , said  
method comprising: producing a fluorine-doped SiO<sub>2</sub> cladding glass ~~[(4)]~~ on a core glass  
cylinder ~~[(3)]~~ rotating about ~~[its]~~ a longitudinal axis thereof, including feeding ~~[in-that]~~ a  
plasma burner ~~[(1)-is-fed]~~ with a silicon-containing starter substance, said starter substance  
being ~~[is]~~ oxidized in a plasma flame ~~[(2)-assigned-to]~~ of the plasma burner ~~[(1)]~~ to obtain  
SiO<sub>2</sub> particles, and depositing the SiO<sub>2</sub> particles ~~[are-deposited]~~ in layers on a ~~[the]~~  
cylindrical outer surface of the core glass cylinder ~~[(2)]~~ in the presence of fluorine and  
sintering said SiO<sub>2</sub> particles deposited ~~[are-sintered]~~ into the cladding glass ~~[(4)]~~, wherein  
~~[characterized-in-that-a]~~ said plasma flame ~~[(2)-which]~~ emits ultraviolet light ~~[of]~~ in one or  
more wavelengths in a range about a wavelength of 214 nm ~~[with]~~ at an intensity of at least  
0.9 μW, determined on the basis of ~~[the]~~ a plasma flame intensity measurement, ~~[is-used-for]~~  
during the forming and depositing of the SiO<sub>2</sub> particles on the core glass cylinder ~~[(3)]~~.
2. (currently amended) The method according to claim 1, ~~[characterized-in-that-a]~~  
wherein the plasma flame ~~[(2)-is-used-which]~~ emits said ultraviolet light ~~[of-a-wavelength~~  
~~of 214 nm-with]~~ at an intensity ranging from 1.0 μW to 1.4 μW.
3. (currently amended) The method according to ~~[any one of the preceding claims,~~  
~~characterized-in-that]~~ claim 1, wherein the cylindrical outer surface of the core glass  
cylinder ~~[(3)]~~ is kept at a surface temperature ranging from 1550°C to 2000°C during

deposition of the SiO<sub>2</sub> particles, and [~~that~~] wherein the core glass cylinder [~~(3)~~] has an outer diameter of at least 40 mm.

4. (currently amended) The method according to claim 3, [~~characterized in that~~] wherein the cylindrical outer surface of the core glass cylinder [~~(3)~~] is kept at a surface temperature ranging from 1700°C to 1900°C during deposition of the SiO<sub>2</sub> particles, and [~~that~~] wherein the core glass cylinder [~~(3)~~] has an outer diameter of at least 60 mm.

5. (currently amended) The method according to claim 1, wherein [~~any one of the preceding claims, characterized in that~~] the SiO<sub>2</sub> particles are deposited on the cylindrical outer surface in layers having [~~with~~] a layer thickness [~~in~~] such [~~a manner~~] that optical fibers derived from the preform have optical fiber [~~they yield~~] layers yielded by the layers of the deposited SiO<sub>2</sub> particles, and said optical fiber layers have respective [~~with~~] layer thicknesses of not more than 0.05 µm in the optical fibers.

6. (currently amended) A method for producing a preform for optical fibers [~~by~~], said method comprising:

providing a cladding glass tube [~~consisting~~] of fluorine-doped quartz glass for cladding a core glass cylinder, wherein said cladding glass tube is produced by supplying [~~with~~] a silicon-containing starter substance [~~being supplied~~] to a plasma burner [~~for producing the cladding glass tube~~], said plasma burner having a plasma flame that oxidizes said substance [~~being oxidized in a plasma flame assigned to the plasma burner to form~~] forming SiO<sub>2</sub> particles, [~~and the~~] said SiO<sub>2</sub> particles being deposited in layers in the presence of fluorine on a [~~the~~]

cylindrical outer surface of a substrate tube which is rotating about ~~[its]~~ a longitudinal axis thereof and is made from quartz glass, and wherein said particles ~~[being]~~ are sintered, ~~[characterized in that the]~~ collapsing said cladding glass tube ~~[is collapsed]~~ onto ~~[the]~~ said core glass cylinder, and ~~[that the]~~ removing said substrate tube ~~[is removed]~~ prior to collapsing said cladding glass tube.

7. (currently amended) The method according to claim 6, ~~[characterized in that the]~~ wherein said substrate tube is removed by etching.

8. (currently amended) The method according to claim 6 ~~or 7~~, ~~[characterized in that the]~~ wherein said substrate tube is etched off during production of the cladding glass tube by introducing an etching gas.

9. (currently amended) The method according to claim 8, ~~[characterized in that]~~ wherein said etching gas is SF<sub>6</sub> ~~[is used as the etching gas]~~.

10. (currently amended) The method according to claim ~~[any one of claims]~~ 6 ~~[to 9]~~, ~~[characterized in that a]~~ wherein said substrate tube ~~[is used having]~~ has a wall thickness ranging from 2 mm to 10 mm.